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Displacement Damage Defect : Improving NIEL scaling

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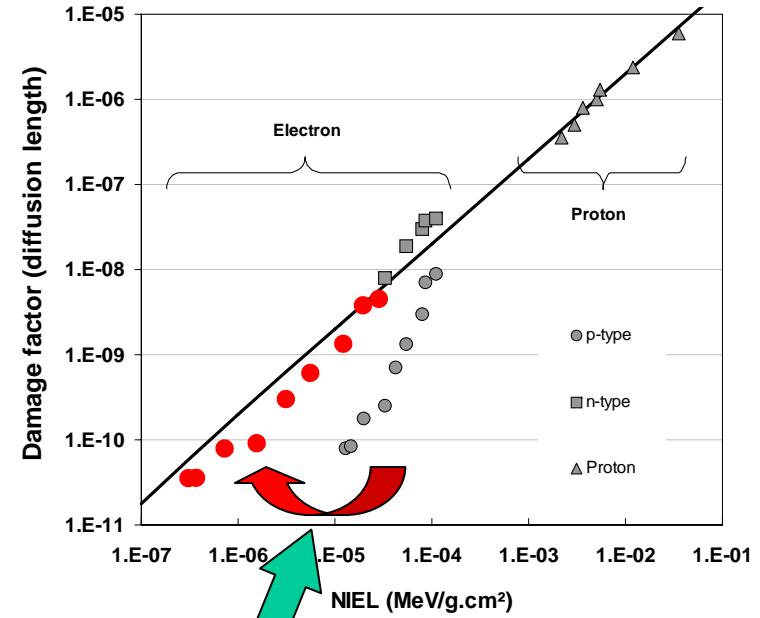
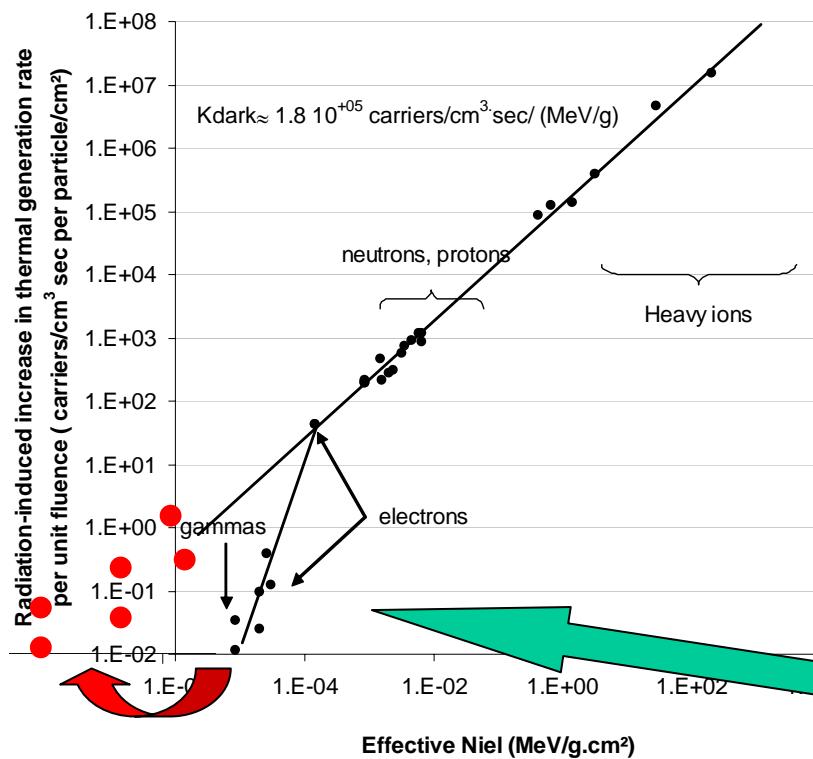


r e t o u r s u r i n n o v a t i o n



Introduction : NIEL scaling

- NIEL fails sometimes to predict degradation rate due to displacement damages



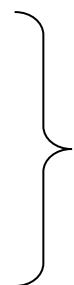
Quadratic variation

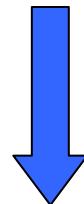
J. R. Srour, J. W. Palko "A framework for understanding displacement damage mechanisms in irradiated silicon devices," IEEE Trans. Nucl. Sci., vol. NS-53, no6, December 2006.

G. P. Summers, E. A. Burke, P. Shapiro, S. Messenger, R.J. Walters , IEEE Trans. Nucl. Sci., vol. 40, No. 6, pp. 1372-1379, December 1993.

C. Inguimbert, P. Arnolda, T. Nuns, G. Rolland IEEE Trans. Nucl. Sci., vol. NS-57, no4, 2010

Goal

- Improving Displacement Damage degradation prediction
 - Improving NIEL
 - Improving Monte Carlo transport codes
- 
- BCA hypothesis**



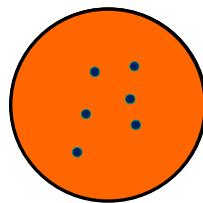
**Incorporating for displacement analysis
the "improved BCA" method in a GEANT 4
application**

Outline

- Introduction
- NIEL improvement for **silicon**
 - Principle of the calculation
 - Comparison with measured defects introduction rates
- Conclusion
- Outlook

Amorphous pockets

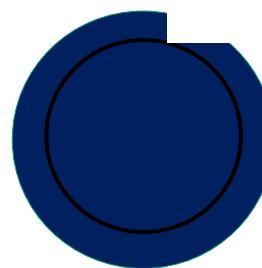
- Competition between melting and diffusion of energy processes
- Importance of deposited energy density Santos & al. [5, 6]
- Collective motion that allows displacement damages generation below the traditional threshold ($T_d \sim 21$ eV in Si)



1eV/atom



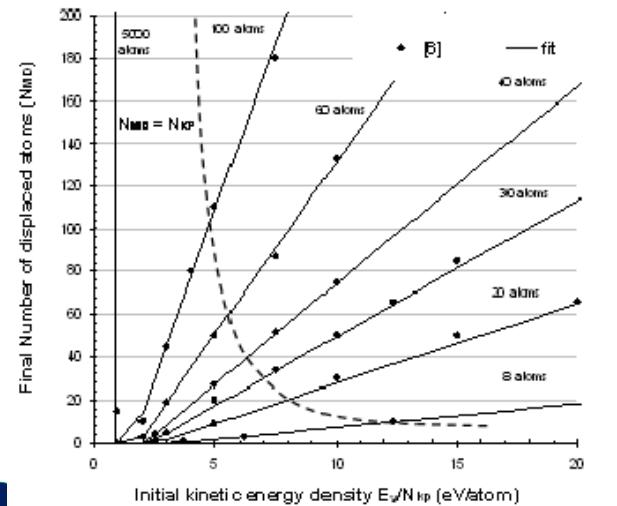
2eV/atom



5eV/atom

BCA

$$\text{Number of displacements} = 0.4 \frac{G(E)}{T_d}$$

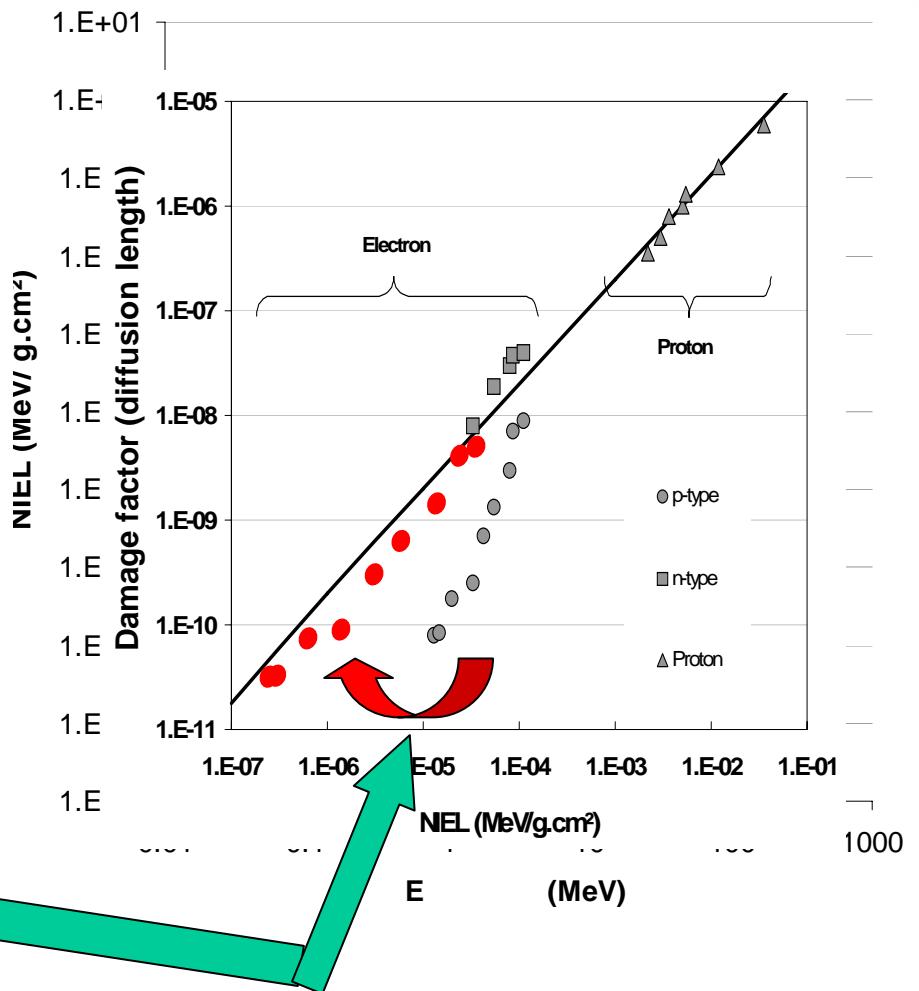
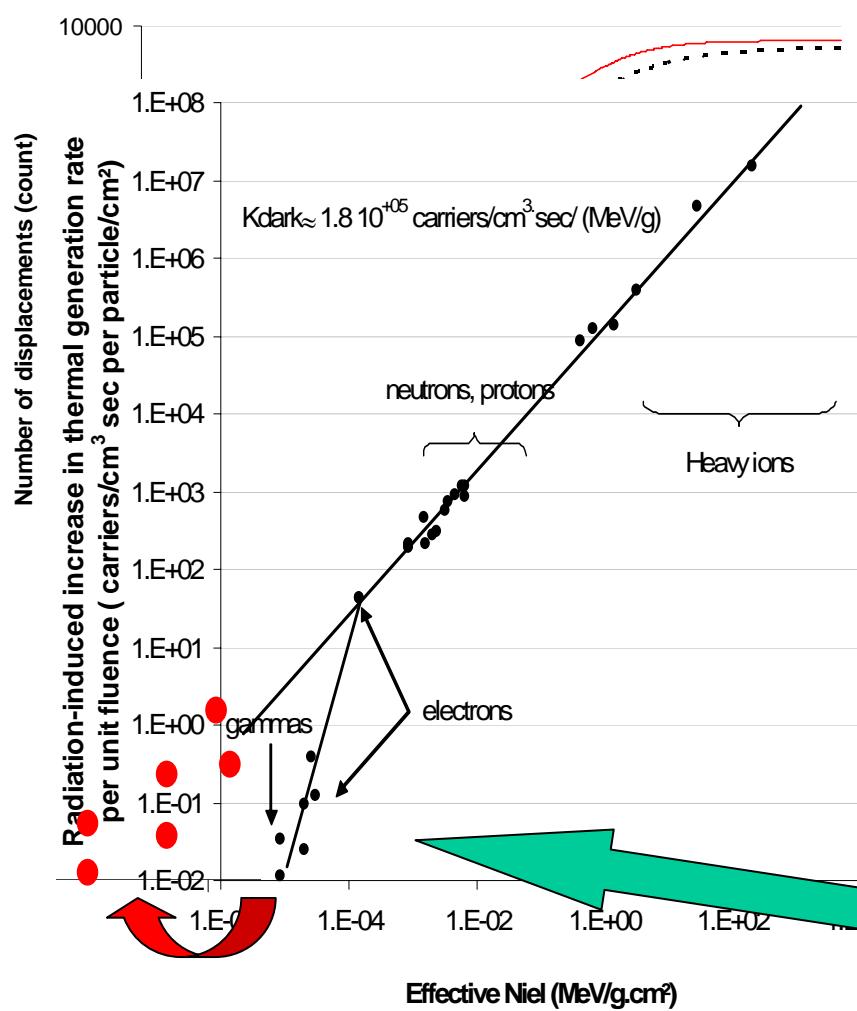


- Size initial moving atoms
- Size final pocket

[5] I. Santos, L. Marques, P. Lourdes, " Modeling of damage generation mechanisms in silicon at energies below the displacement threshold, " Physical Review B 74, 174115 (2006).

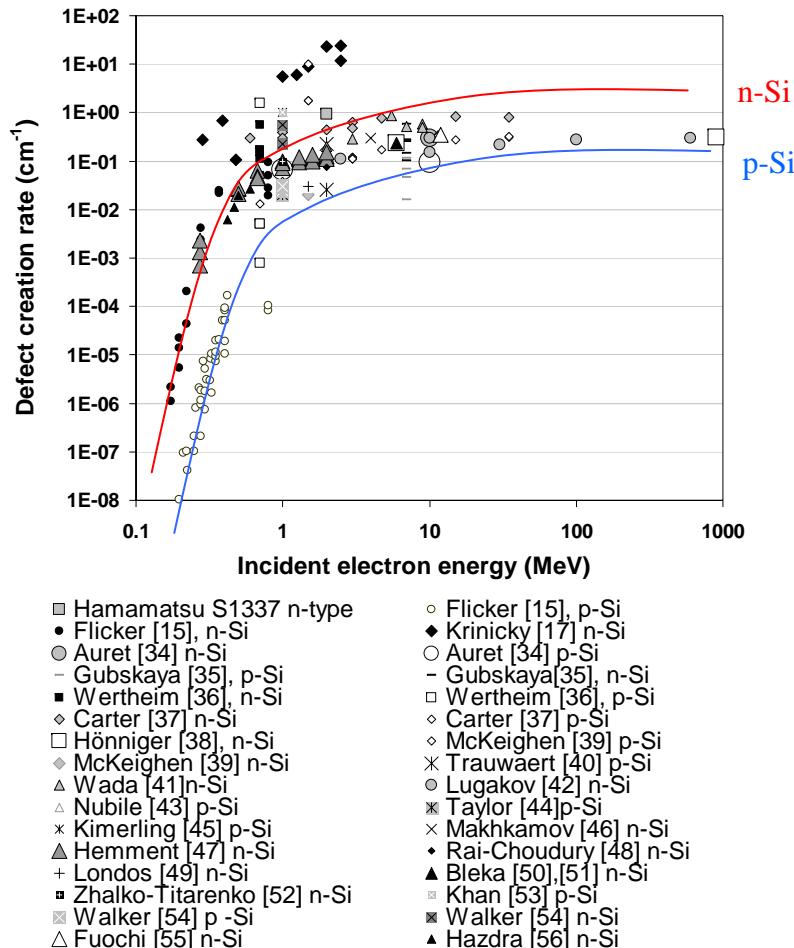
[6] I. Santos, L. Marques, P. Lopez, " Molecular dynamics study of damage generation mechanisms in silicon at the low energy regime, " Electron Devices, 2007 Spanish Conference on, pp. 37-40, 02 February 2007.

Amorphous pockets



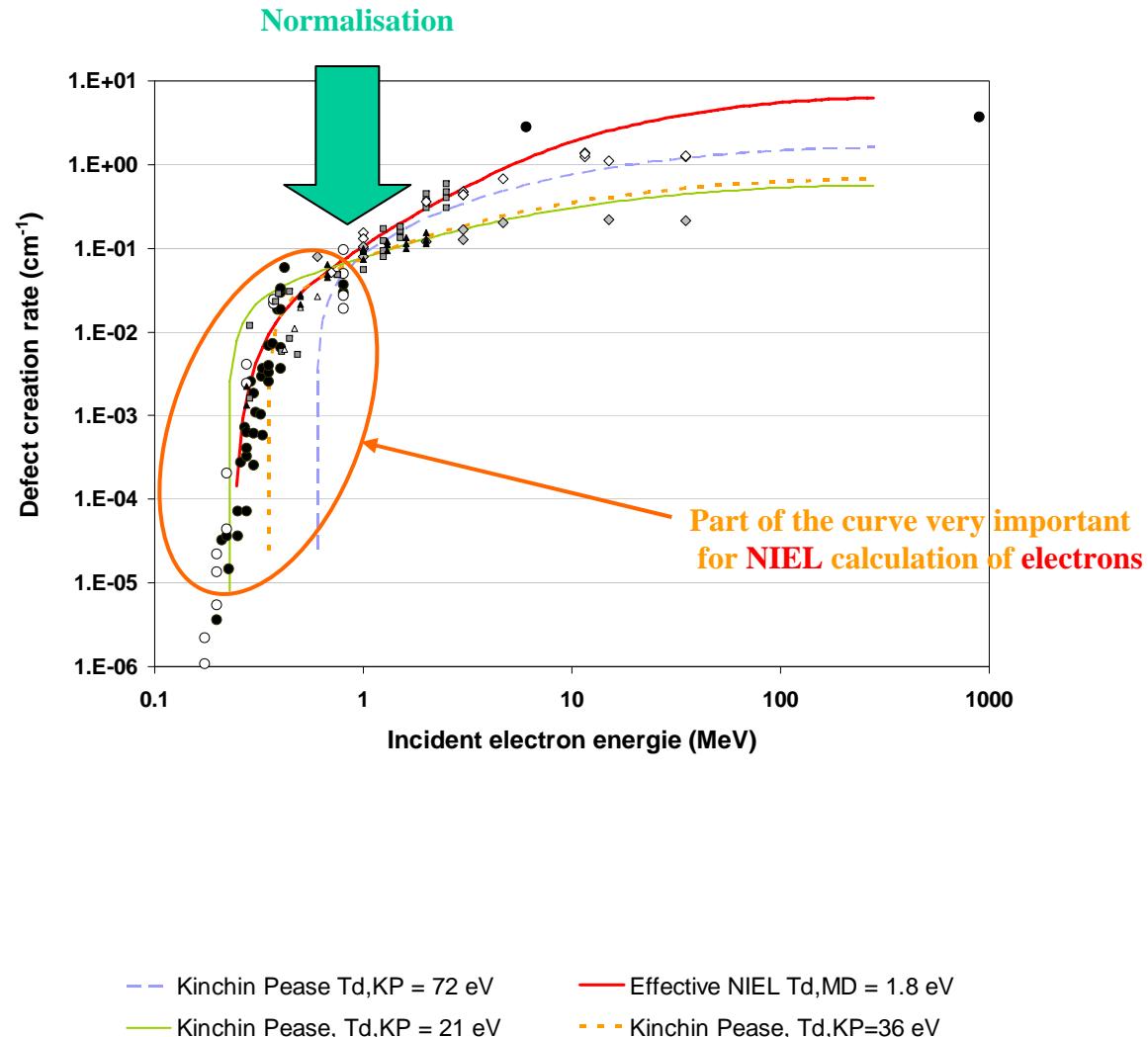
C. Inguimbert, P. Arnolda, T. Nuns, G. Rolland IEEE Trans. Nucl. Sci., vol. NS-57, no4, 2010

Bibliographic data : defects introduction rates for electrons in silicon

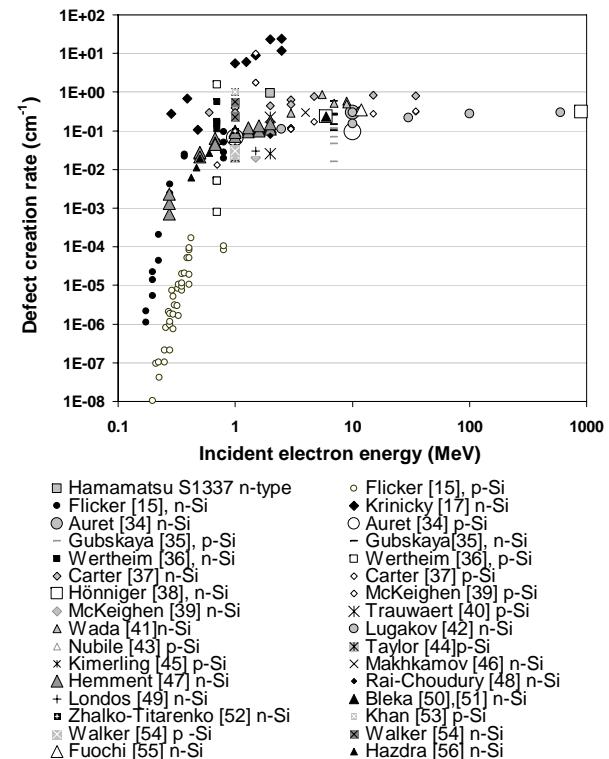
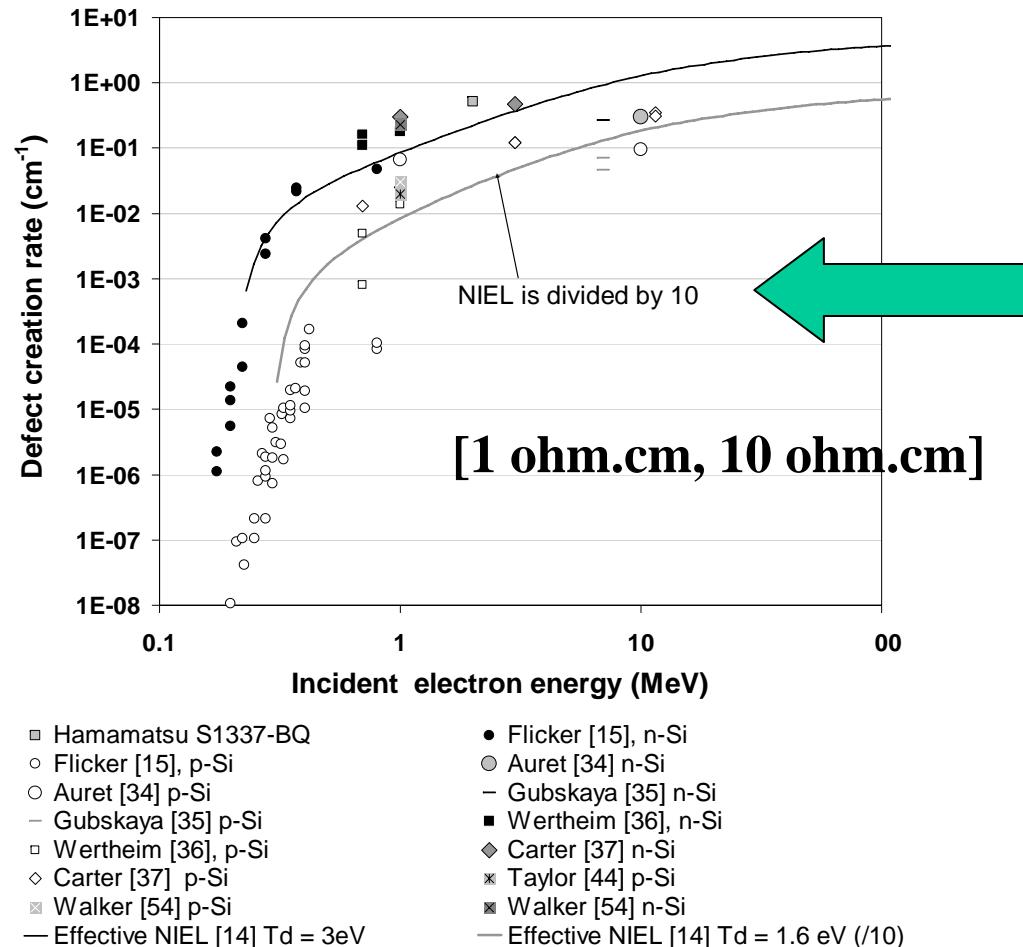


M. J. Beck, L. Tsetseris, M. Caussanel, R. D. Schrimpf, D. M. Fleetwood, and S. T. Plantelides, "Atomic scale Mechanisms for low-NIEL dopant-type dependent damage in Si, " IEEE Trans. Nucl. Sci., vol. NS-53, no6, pp. 1372-1379, December 2006.

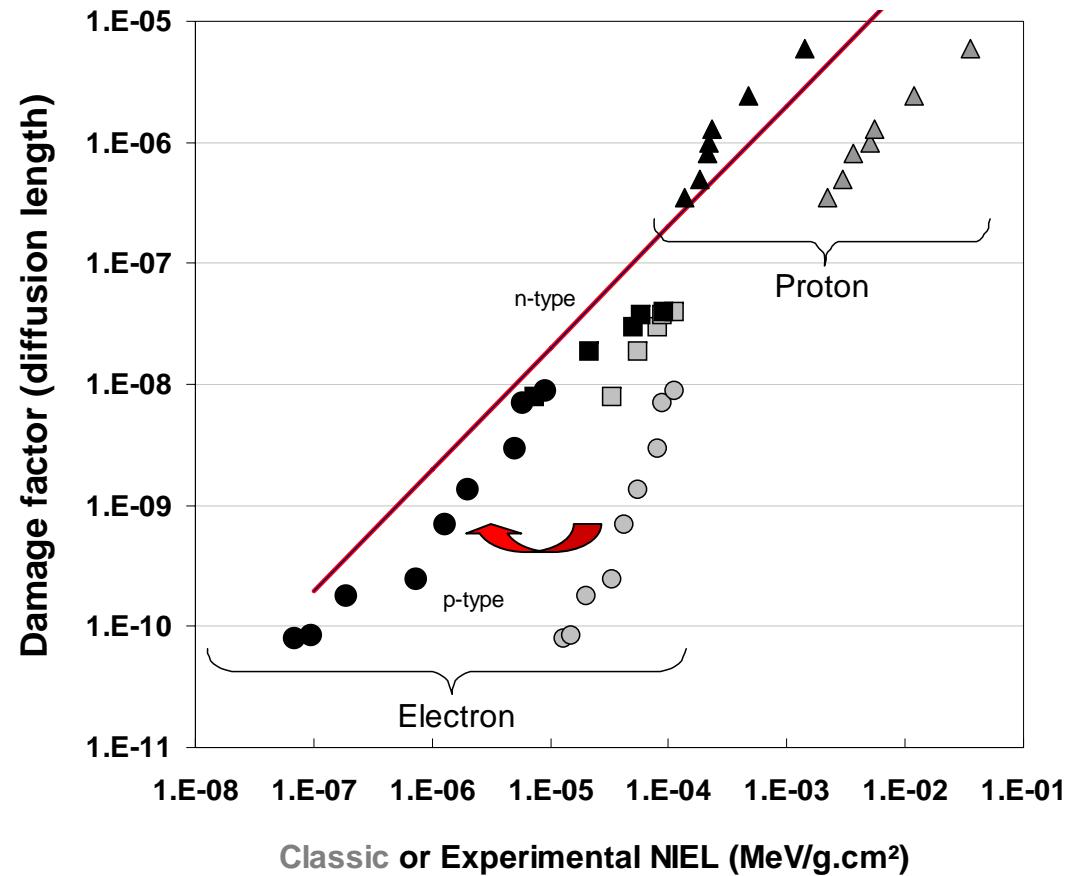
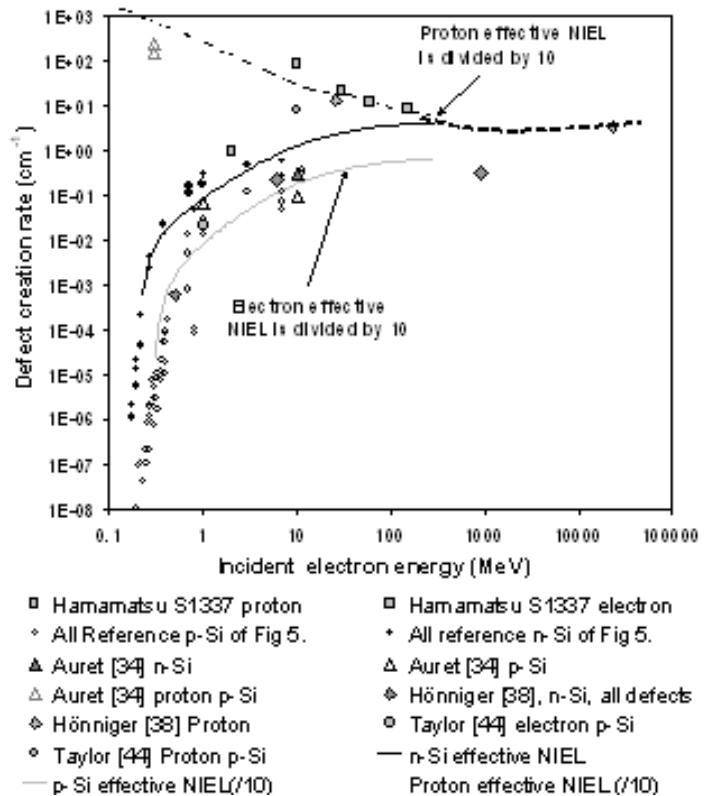
New NIEL calculation



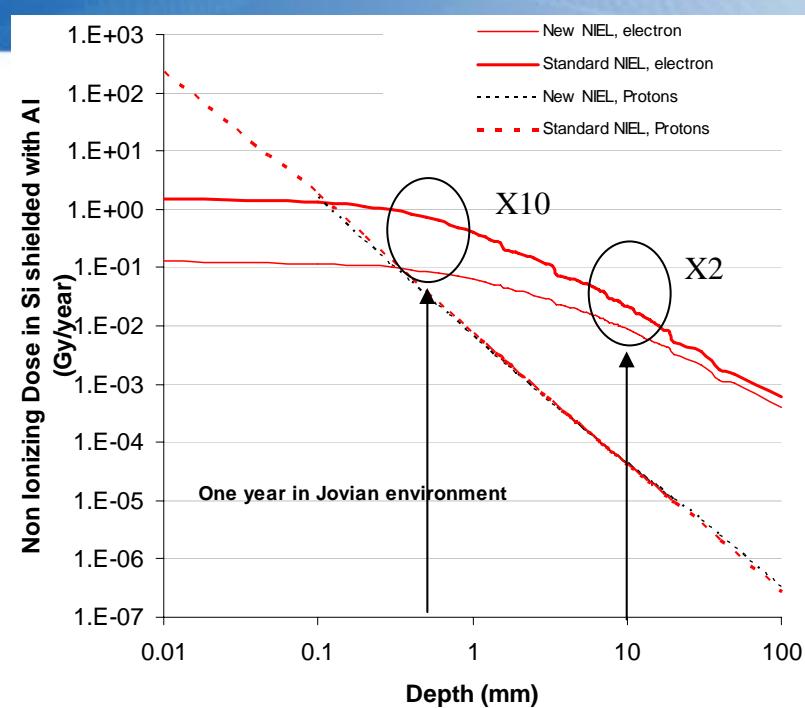
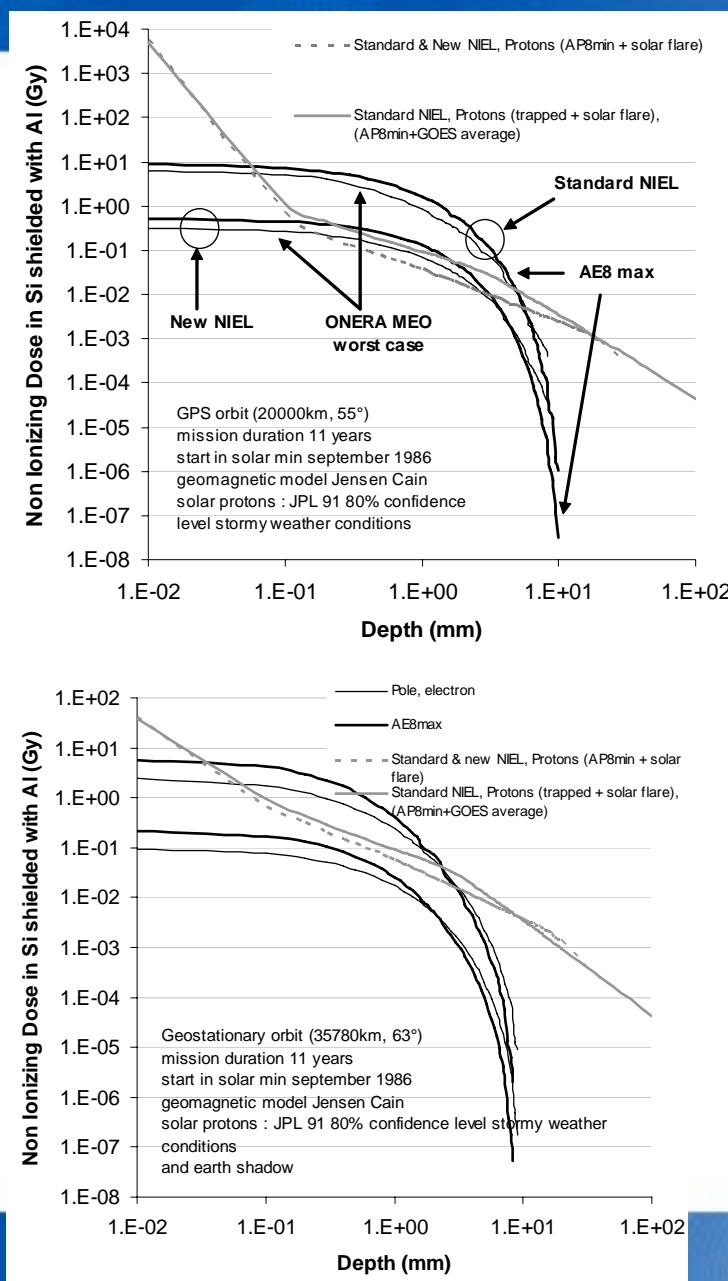
Defect introduction rate : comparison with experiments



Scaling degradation rate



Displacement Damage Dose profile



**Electron constraint reduced between
a factor 2 and a factor 10**

Conclusion

Demonstrated for silicon

- Non linear effects, for low energy PKAs, (amorphous pockets)
- MD simulation are used to calculate a new energy partition function for Silicon and new NIEL (Electrons)
- Mixing calculation and defect introduction rate measurements leads to a better degradation prediction

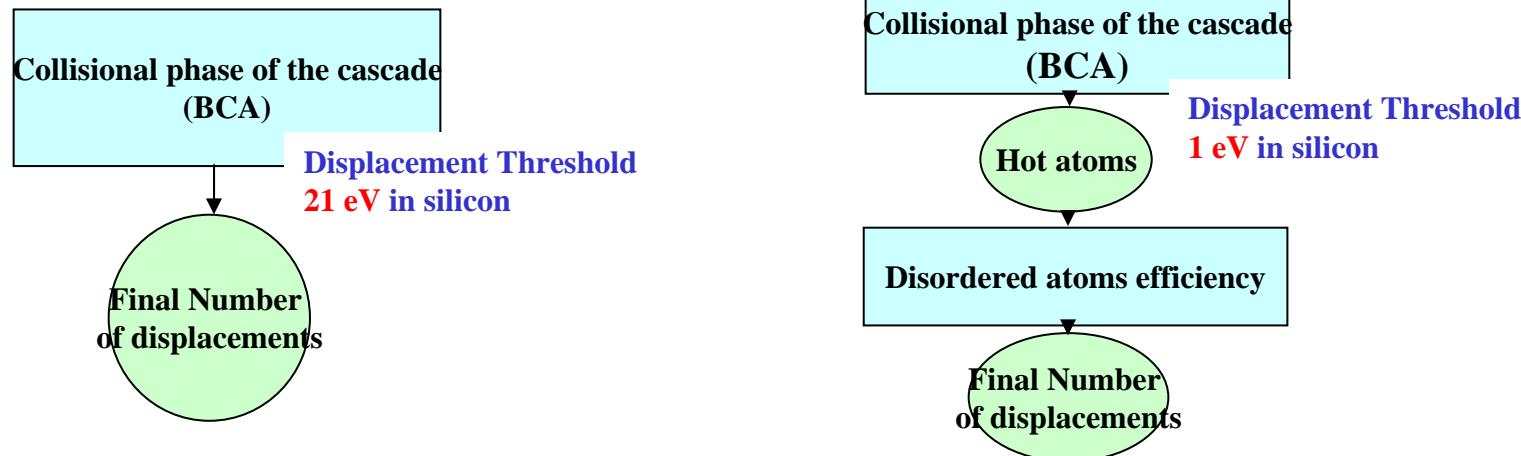
Otlook : Improved BCA approach

Improving NIEL scaling method

Extending MD simulations for other materials (GaAs, InP, ...)

In order to define a new energy partition function and new NIELs tables

- Monte Carlo (GEANT 4) implementation



Perspectives : GEANT4 User Interface

- Incorporating the Improved BCA approach within a GEANT 4 user Interface
- Our own G4 interface demonstrator
 - Based on Input/Output file library

